

ABSTRACT OF THE DISCLOSURE

A bonding apparatus is constituted by a bonding tool,
a substrate stage, a moving mechanism for moving the bonding
tool and the substrate stage, an up-and-down mechanism for
moving up and down said bonding tool, and a chip recognition
camera. The bonding apparatus is configured so that a chip
and a substrate are subjected to positioning on the basis of
a recognition result of the chip recognition camera so that
the chip is bonded onto the substrate. The chip recognition
camera is disposed to be lower than a level of a substrate
mounted surface of the substrate stage. A lower surface of
the chip is recognized in a condition that the lower surface
of the chip is located to be substantially on a level with
a chip bonding surface of the substrate. Positioning of the
chip and the substrate is performed by the recognition image.